

I. Jovanovic, S. N. Dixit, B. Wattellier, M. R. Hermann, C. P. J. Barty

This article was submitted to 2003 Conference on Lasers and Electro-Optics Quantum Electronics and Laser Science Conference, Baltimore, MD, June 1-6, 2003

U.S. Department of Energy





DISCLAIMER

This document was prepared as an account of work sponsored by an agency of the United States Government. Neither the United States Government nor the University of California nor any of their employees, makes any warranty, express or implied, or assumes any legal liability or responsibility for the accuracy, completeness, or usefulness of any information, apparatus, product, or process disclosed, or represents that its use would not infringe privately owned rights. Reference herein to any specific commercial product, process, or service by trade name, trademark, manufacturer, or otherwise, does not necessarily constitute or imply its endorsement, recommendation, or favoring by the United States Government or the University of California. The views and opinions of authors expressed herein do not necessarily state or reflect those of the United States Government or the University of California, and shall not be used for advertising or product endorsement purposes.

This is a preprint of a paper intended for publication in a journal or proceedings. Since changes may be made before publication, this preprint is made available with the understanding that it will not be cited or reproduced without the permission of the author.

This work was performed under the auspices of the United States Department of Energy by the University of California, Lawrence Livermore National Laboratory under contract No. W-7405-Eng-48.

This report has been reproduced directly from the best available copy.

Available electronically at http://www.doc.gov/bridge

Available for a processing fee to U.S. Department of Energy
And its contractors in paper from
U.S. Department of Energy
Office of Scientific and Technical Information
P.O. Box 62
Oak Ridge, TN 37831-0062

Telephone: (865) 576-8401 Facsimile: (865) 576-5728 E-mail: reports@adonis.osti.gov

Available for the sale to the public from U.S. Department of Commerce National Technical Information Service 5285 Port Royal Road Springfield, VA 22161 Telephone: (800) 553-6847 Facsimile: (703) 605-6900

E-mail: <u>orders@ntis.fedworld.gov</u>
Online ordering: <u>http://www.ntis.gov/ordering.htm</u>

OR

Lawrence Livermore National Laboratory
Technical Information Department's Digital Library
http://www.llnl.gov/tid/Library.html

Feasibility of thin Fresnel lens use in multi-kJ, short pulse laser systems

Igor Jovanovic, Sham N. Dixit, Benoit Wattellier, Mark R. Hermann, and C. P. J. Barty
Lawrence Livermore National Laboratory, Mail Code L-490, 7000 East Avenue, Livermore, California 94550
jovanovic @llnl.gov

Abstract: Recently-developed, thin-Fresnel-lens technology offers the potential for transmissive focusing of high-peak-power, ultrashort-duration laser pulses. Calculations of the transverse and longitudinal spectral blurring effects of thin Fresnel lenses when used to focus ultrashort, high-energy laser pulses are presented.

©2002 Optical Society of America

OCIS codes: (050.1970) Diffraction and gratings: Diffractive optics; (140.7090) Ultrafast lasers

High-peak-power, short-pulse laser systems have traditionally used reflective optics to focus laser pulses to avoid linear and nonlinear phase accumulation inherent to refractive optics. Typical recompressed pulses from a large Nd:glass laser have an unfocussed intensity of order 1 TW/cm². When incident on a transmissive fused silica optic, such pulses would produce a B-integral of ~20 cm²-200 cm². High B-integral (>1) will lead to focal spot distortion, and possibly to self focusing and damage of the focusing optic. Reflective parabolic focusing optics eliminate the B-integral problem and are widely used in short pulse laser systems. However, the surface quality requirements for a reflective optic are typically much higher, and their tolerance to beam pointing and divergence is up to one order of magnitude lower than for a corresponding transmissive optic.

Recently, Lawrence Livermore National Laboratory has developed the capability to produce, high quality thin Fresnel lenses. [1] Lenses with thicknesses <200 µm and apertures up to 60 cm have been shown to be capable of producing diffraction-limited beam quality focal spots. Transmission through such lenses would produce negligible B-integral (<<1). However, chromatic aberrations inherent to Fresnel lenses will distort the focal spot size and pulse duration. Such distortions will be strong functions of the input pulse bandwidth and the f-number of the optical system. Next generation large laser systems such as the National Ignition Facility (NIF) in the US and the Laser MegaJoule (LMJ) in France have the potential to produce multi-kJ short pulses and operate with high f-number final optics. In this paper we numerically evaluate the feasibility of thin Fresnel lens use for focusing of high-power laser pulses.

The chromacity of the Fresnel lens results in reduced transverse focusability of a spectrally broadband beam. In Figs. 1 and 2 we show representative results of our calculations for transverse focal spot blurring assuming an input beam profile similar to that which will be produced by NIF or LMJ and a bandwidth corresponding to a 2-ps transform-limited pulse.

A beam incident on a Fresnel lens also experiences radially variable transit time to focus. We calculated the pulse duration at focus for an incident Gaussian temporal pulse (Fig. 3).

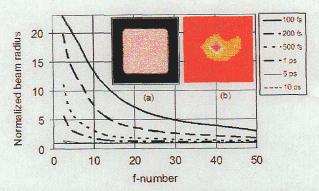


Fig. 1. Transverse focal spot blurring as a function of the Fresnel lens f-number, for several representative pulse widths. Calculated broadband beam radius is normalized to the monochromatic focused beam radius. Inset: (a) NIF near-field amplitude profile, (b) NIF focal spot, for f/#=10 and 100-fs pulse duration.

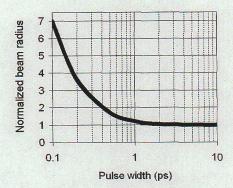


Fig. 2. Transverse focal spot blurring as a function of transform-limited pulse width, for f/#=17. Calculated broadband beam radius is normalized to the monochromatic focused beam radius.

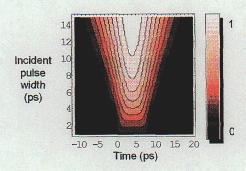


Fig. 3. Focused pulse intensity, for a range of incident pulse durations. Pulse intensity is normalized to the intensity of an ideally focused monochromatic beam.

If the criteria for acceptable pulse focusing is defined as <50% spatial blurring, the minimum acceptable f-number for focusing of 1-ps pulses is \sim 12.5. For a <50% decrease in peak intensity of an incident 0.4-m diameter, 1053-nm pulse, focused with f_0 =8 m, the minimum pulse width allowed on the lens is \sim 4 ps. While those requirements may be too restrictive for some short-pulse laser systems, they are acceptable for applications such as hard x-ray generation with laser based relativistic electrons [2] and could be applicable to low energy applications such as precision micromachining, with high-average power CPA systems. Practical limits as a function of pulse bandwidth and lens f-number for a variety of short pulse systems will be presented.

This work was performed under the auspices of the U. S. Department of Energy by Lawrence Livermore National Laboratory under Contract No. W-7405-Eng-48.

- I. M. Barton, J. A. Britten, S. N. Dixit, L. J. Summers, I. M. Thomas, M. C. Rushford, K. Lu, R. A. Hyde, and M. D. Perry, "Fabrication of Large-Aperture Lightweight Diffractive Lenses For Use in Space," Appl. Opt. 40, 447-451 (2001).
 T. Guo, Ch. Spielmann, B. C. Walker, and C. P. J. Barty, "Generation of hard X-rays by ultrafast terawatt lasers," Rev. Sci. Instrum. 72, 41-47 (2001).